



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Saburo KAMIYA

Group Art Unit: 2877

Application No.: 09/661,433

Examiner: S. Turner

Filed: September 13, 2000

Docket No.: 107312

For: EXPOSURE APPARATUS AND DEVICE PRODUCTION METHOD IN WHICH POSITION OF REFERENCE PLATE PROVIDED ON SUBSTRATE STAGE IS MEASURED (AS AMENDED)

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

1. This Information Disclosure Statement is being filed with a Request for Continued Examination. No certification or fee is required.

Respectfully submitted,

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MAC/ccs

Date: March 3, 2003

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